

A1 09/493,978, filed January 28, 2000, entitled "SYSTEM METHOD FOR CONTROLLED POLISHING AND PLANARIZATION OF SEMICONDUCTOR WAFERS," by Rod Kistler and Yehiel Gotkis, and such related application is hereby incorporated by reference.--

**REMARKS**

The Applicants are hereby amending the specification to correct the application number which was provided erroneously as 09/664,135, but should have been 09/644,135.

Respectfully Submitted,  
MARTINE PENILLA & KIM, LLP



Albert S. Penilla, Esq.  
Reg. No. 39,487

09748708.050701

710 Lakeway Drive, Suite 170  
Sunnyvale, CA 94085  
Telephone (408) 749-6900  
**Customer Number 25,920**